

### **Amendments to the Claims:**

This listing of claims will replace all prior versions, and listings, of claims in the application:

### **Listing of Claims:**

1. (Currently Amended) A high yield fixture for the production of demultiplexer filters for dense wavelength division multiplexers, the fixture comprising:

a disk with a concentric aperture , the disk adapted to be rotatable at greater than 2400 rpm during operation;

a dedicated multi-crystal quartz crystal thickness monitor positioned within the concentric aperture;

an optical thickness monitor;

a clam shell shutter;

a magnetic induction rotation mechanism; and,

multiple substrates, ~~the substrates located concentrically~~ rigidly attached to the disk and arranged radially about the concentric aperture containing the quartz crystal monitor.

2. (Currently Amended) A high yield fixture for production of optical filters, the fixture comprising:

a rotating disk with a concentric aperture member;

a thickness monitor arranged within said aperture;  
a shuttering means for shuttering the disk fixture;  
at least one substrate; said substrate rigidly attached to the disk and,  
rotating means for rotating the fixture.

3. (Currently Amended) The fixture of claim 2, wherein the ~~rotating member~~  
~~is a disk~~ is adapted to be rotated at greater than 500 rpm.

4. (Original) The fixture of claim 3, wherein the thickness monitor is a  
dedicated quartz crystal monitor.

5. (Original) The fixture of claim 4, wherein the shuttering means is a clam  
shell shutter.

6. (Currently Amended) The fixture of claim 5, wherein the fixture further  
comprises:

multiple substrates, ~~the substrates~~ rigidly attached to the disk and arranged  
radially about the concentric aperture located concentrically about the monitor.

7. (Canceled).

8. (Currently Amended) The fixture of claim 2 [[7]], wherein the rotating  
means is a magnetic induction rotation mechanism.

9. (Canceled) .

10. (Currently Amended) A high speed substrate assembly for use in a line-of-  
sight deposition process, the assembly comprising:

multiple independent fixtures,

the fixtures comprising:

a rotating disk with a concentric aperture;

at least one thickness monitor arranged within said concentric aperture;

at least one substrate; said substrate rigidly attached to the disk;

shuttering means for shuttering the fixture; and, rotating means for rotating

the disk fixture.

11. (Original) The assembly of claim 10, wherein the at least one thickness monitor further comprises:

a dedicated quartz crystal monitor; and,

an optical thickness monitor.

12. (Currently Amended) The assembly of claim 11, wherein ~~the fixtures further comprise:~~

~~a rotatable disk, the at least one substrate and~~ the monitors being rigidly connected to ~~located on~~ the disk.

13. (Currently Amended) The assembly of claim 12, wherein the at least one substrate is multiple substrates, the substrates being ~~concentrically~~ located about the concentric aperture and around the quartz crystal monitor.

14. (Original) The assembly of claim 13, wherein the shuttering means is a clam shell shutter.

15. (Original) The assembly of claim 14, wherein the rotating means is a magnetic induction rotation mechanism.

16.-20. (Canceled)